

Japan PI&C Committee Meeting Summary and Minutes

Japan Standards Summer Meetings 2013
September 4, 2013, 13:30-17:30
JPR Bldg. Conference Room1, SEMI Japan office, Tokyo, Japan

Next Committee Meeting

December 6, 2013, 9:00a.m.-12:00a.m. Japan Standard Time
SEMICON Japan 2013, Makuhari Messe, Chiba, Tokyo

Committee Announcements (optional)

None

Table 1 Meeting Attendees

Co-Chairs: Tsuyoshi Nagashima (Miraial), Tsutomu Okabe (TDK), Kenji Yamagata (Daifuku)

SEMI Staff: Hirofumi Kanno

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Shimizu Consulting	Shimizu	Yasuhiro	Sinfonia Technology	Otani	Mikio
Hitachi Kokusai	Matsuda	Mitsuhiro	Hitachi Hi-Tech	Sato	Hidetoshi
Dainichi Shoji	Ohyama	Koji	SUMCO	Nakai	Tetsuya
Tokyo Electron	Mashiro	Supika	Consultant	Kumai	Sadao
Intel	Nojima	Takao	Acteon	Komatsu	Shoji
Murata Machinery	Murata	Masanori	TDK	Okabe	Tsutomu
Miraial	Nagashima	Tsuyoshi	Daifuku	Yamagata	Kenji

Table 2 Leadership Changes

<i>Group</i>	<i>Previous Leader</i>	<i>New Leader</i>
Fiducial Mark Interoperability Task Force	--	Supika Mashiro / Tokyo Electron

Table 3 Ballot Results

None

Table 4 Authorized Ballots

None

Table 5 Authorized Activities

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
--	TFOF	Fiducial Mark Interoperability Task Force	<p>TF Charter: Standardization of fiducial mark as the alternative to the notch is now under development at the International 450mm Wafer Task Force under the Global Silicon Wafer Committee.</p> <p>Adoption of fiducial mark will affect not only Si wafer specification and related Standards but also Standards owned by other Global Technical Committees that reference the Notch. Furthermore, as readability of fiducial mark may change due to intentional and unintentional interaction of wafer surface and various tools in their process apparatuses and with wafer handling mechanisms, standardization of fiducial mark detection data and their communication is deemed necessary to support traceability and to compensate deteriorated readability of Fiducial Mark.</p> <p>In order to address above cross disciplinary challenge, this Task Force is established</p>

Table 5 Authorized Activities

#	Type	SC/TF/WG	Details
			under five Global Technical Committees (Silicon Wafer TC, PI&C TC, I&C TC, Assembly & Packaging TC and Traceability TC), and develops the Standards to support the fiducial mark.

Note: SNARFs and TFOFs are available for review on the SEMI Web site at:
<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 6 New Action Items (or move to Section 8, Action Item Review)

Item #	Assigned to	Details
130904-1	Shoji Komatsu (Acteon)	For the modified charter of the Japan PIC Committee approved, Shoji Komatsu and Larry Hartsough review the editorial changes indicated in discussion during the Japan PIC Committee meeting on September 4, 2013.

Table 7 Previous Meeting Actions Items (or move to Section 8, Action item Review)

Item #	Assigned to	Details
130606-1	Supika Mashiro (Tokyo Electron)	Supika Mashiro to ask the EHS Committee for feedback about the document activity of Specification for Signal Tower for 450mm AMHS through PI&C Liaison report to the EHS Committee. → Open

1 Welcome, Reminders, and Introductions

Tsuyoshi Nagashima called the meeting to order at 1:30 p.m. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting.

Motion: Approve the minutes of the previous meeting
By / 2nd: Kenji Yamagata (Daifuku) / Mitsuhiro Matsuda (Hitachi Kokusai)
Discussion: None
Vote: 12:0

3 Liaison Reports

3.1 Europe Equipment Automation Committee

Hirofumi Kanno (SEMI) reported for the Europe Equipment Automation Committee. Of note:

- Meeting Information
- Committee Chairmen
- Committee Structure
- Leadership Changes
- Ballot Results
- New SNARF
- Task Forces Activities

Attachment: 1, EA Liaison Report_April 2013

3.2 North America PIC Committee

Hirofumi Kanno (SEMI) reported for the North America PIC Committee. Of note:

- Meeting Information
- Committee Chairmen
- Committee Structure
- Leadership Changes
- Ballot Results
- New SNARF
- Task Forces Activities

Attachment: 2, NA PIC Report Aug 2013 MT

3.3 SEMI Staff Report

Hirofumi Kanno (SEMI) gave the SEMI Staff Report. Of note:

- Global SEMI Events
- Global Standards Meetings Schedule
- Ballot Critical Dates
- Publication Update
- ISC A&R SC Summary May and June 2013
- Preparation for SEMICON Japan 2013
- Contact Information

Attachment: 03, SEMI Staff Report 2013 Aug. R0.1

4 Subcommittee & Task Force Reports

4.1 Global PIC Standards Maintenance TF

Shoji Komatsu (Acteon) reported there was no activity for the Global PIC Standards Maintenance Task Force.

4.2 450 mm Int'l PIC TF

Shoji Komatsu reported for the 450 mm Int'l PIC Task Force. This report contained information below.

- About z45&z26, Revise the E158 (450FOUP) in Table 1.
- PGV docking flange
- Door closure force & clamping force

Attachment: 04, 450mmIPIC-TF_Report_130904

4.3 Int'l Process Module Physical Interface TF

Supika Mashiro (Tokyo Electron) reported for the Int'l Process Module Physical Interface Task Force.

The TF worked with the 450 IPIC TF on the EFEM Pocket Volume. The TF submitted Doc. 5626 for Cycle 6 or 7 to add the EFEM Pocket Volume to SEMI E145 (450mm Loadport) and SEMI E159 (MAC).

4.4 450 mm AMHS TF

Kenji Yamagata (Daifuku) reported for the 450 mm AMHS Task Force. This report contained information below.

- Working on the development of revised E156
- Collecting information for standardization on signal tower for AMHS.

Motion: Approve the modified SNARF (Doc.5524) for *Revisions to SEMI E156-0710, Mechanical Specification for 450 mm AMHS Stocker to Transport Interface, with title change to MECHANICAL INTERFACE SPECIFICATION FOR 450 mm AMHS STOCKER TO TRANSPORT EQUIPMENT*

By / 2nd: Kenji Yamagata (Daifuku) / Mitsuhiro Matsuda (Hitachi Kokusai)

Discussion: The ballot will be issued next year.

Vote: 12:0

Attachment: 05, 20130904JA 450mm AMHS TF Report R0.0

Attachment: 06, 5524 SNARF rev1 20130904

4.5 Int'l Reticle SMIF Pod & Load Port Interoperability TF

Koji Ohyama (Dainichi Shoji) reported for the Int'l Reticle SMIF Pod & Load Port Interoperability Task Force. This report contained information below.

- No leadership change
- Carrying out a survey for purge port

Attachment: 07, Reticle Pod LP Interoperability TF Report 2013-09 v0-1

4.6 (Silicon Wafer Committee) JA Shipping Box TF / (JA Silicon Wafer Committee and NA PI&C Committee)Int'l 450mm Shipping Box TF

Yasuhiro Shimizu (Shimizu Consulting) reported for the JA Shipping Box Task Force. This report contained information below.

- Rework for a new standard: 450 mm Wafer Shipping System
- Error Correction of SEMI M80-0812
 - Errors in calculation formula for measuring Carrier COG
 - Needs correction for Appendix 3 in M80

Attachment: 08, SHIPPING BOX TF REPORT 2013_09_04

4.7 Updates from Polished /Epi/ASI/AWG TFs(Int'l 450mm related TF) under the global Silicon Wafer Committee

Tetsuya Nakai (SUMCO) reported for the activity. SNARF for revision to M1 was approved by the previous North America Silicon Wafer Committee. Line Items revision of M1 for Wafers for 16nm technology generation SFQR was passed by the North America Silicon Wafer Committee as well.

5 Old Business

None

6 New Business

6.1 Proposal of new TFOF for Fiducial Mark Interoperability Task Force

Mitsuhiro Matsuda (Hitachi Kokusai) addressed the committee on this topic.

This Task Force will set under the following 5 committees.

- Silicon Wafer Committee ← already set up
- PIC Committee ← Today
- PKG Committee ← will set up via GCS approval
- I&C Committee ← will be set up at the next Committee meeting
- Traceability Committee ← will be set up at the next Committee meeting

Motion: Approve the TFOF for the Fiducial Mark Interoperability Task Force

By / 2nd: Mitsuhiro Matsuda (Hitachi Kokusai) / Shoji Komatsu (Acteon)

Discussion: None

Vote: 13:0

Motion: Approve to assign Supika Mashiro as the co-leader of the Fiducial Mark Interoperability Task Force

By / 2nd: Mitsuhiro Matsuda (Hitachi Kokusai) / Shoji Komatsu (Acteon)

Discussion: None

Vote: 12:0

Attachment: 09,20130829FiducialMarkIOTF_R0.2

Attachment: 10, 07.02_20130829FiducialMarkIOTF_R0.2

6.2 SEMI Standards 450mm Seminar

Hirofumi Kannno (SEMI) addressed on this topic

The seminar will be scheduled for Friday December 6, 2013 during SEMICON Japan 2013 at Makuhari Messe, Chiba, Japan.

6.3 Schedule of PIC Committee related Standards meetings during SEMICON Japan 2013

Hirofumi Kanno addressed on this topic

6.4 About PIC TC Charter

Shoji Komatsu addressed on this topic

Shoji Komatsu and Larry Hartsough found some difference between North America PIC Committee charter and Japan PIC Committee charter. They will propose a new description for the charters near future. Shoji Komatsu proposed the modified charter of the Japan PIC Committee at this meeting.

Motion: Approve the modified charter of the Japan PIC Committee

By / 2nd: Shoji Komatsu (Acteon) / Mitsuhiro Matsuda (Hitachi Kokusai)

Discussion: There was a opinion for some editorial changes needed. Shoji Komatsu will talk to Larry Hartsough about them.

Vote: 13:0

Action Item: For the modified charter of the Japan PIC Committee approved by the committee, Shoji Komatsu and Larry Hartsough review the editorial changes indicated in discussion during the Japan PIC Committee meeting on September 4, 2013.

Attachment: 11, PIC Charters Compared v1

7 Action Item Review

7.1 Open Action Items

Hirofumi Kanno (SEMI) reviewed the open action items. These can be found in the Open Action Items table at the beginning of these minutes.

7.2 New Action Items

Hirofumi Kanno (SEMI) reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

8 Next Meeting and Adjournment

The next meeting of the Japan PIC committee is scheduled for Friday December 6 9:00a.m.-12:00a.m. at SMICON Japan 2013 in Makuhari Messe, Chiba, Japan.

Respectfully submitted by:
 Hirofumi Kanno
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Minutes approved by:

<Name> (<Company>), Co-chair	<Date approved>
<Name> (<Company>), Co-chair	<Date approved>

Table 8 Index of Available Attachments #1

#	<i>Title</i>	#	<i>Title</i>
1	EA Liaison Report_April 2013	7	Reticle Pod LP Interoperability TF Report 2013-09 v0-1
2	NA PIC Report Aug 2013 MT	8	SHIPPING BOX TF REPORT 2013_09_04
3	SEMI Staff Report 2013 Aug. R0.1	9	20130829FidutialMarkIOTF_R0.2
4	450mmIPIC-TF_Report_130904	10	07.02_20130829FidutialMarkIOTF_R0.2
5	20130904JA 450mm AMHS TF Report R0.0	11	11_PIC Charters Compared v1(14)
6	5524 SNARF rev1 20130904		

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.